

### **REMARKS**

Claims 1, 4-22 and 24-42 are pending.

Applicant thanks the Examiner's indication that Claims 1, 4-22, 24-39 and 42 are allowed.

Claims 40 and 41 are rejected.

Claim 29 is amended to delete "predetermined" from the claim limitations to be consistent with claim 27.

Claim 40 is amended to include limitations drawn from allowed claim 1.

Claim 41 is amended to be consistent with the language of claim 40 in view of the amendment. In particular, "(c) – (f)" is replaced with "(c) - (h)."

New claim 43 is added. Support for the limitations can be found at page 9, lines 10-24 of the present application.

No new matter is added.

Claims 1, 4-22 and 24-43 remain in the case for reconsideration.

Applicant requests reconsideration and allowance of the claims in light of the above amendments and following remarks.

### ***Claims Rejections – 35 USC § 102***

Claims 40 and 41 are rejected under 35 U.S.C. 102(e) as being anticipated by U.S. Patent No. 6,511,539 B1 Raajimakers ("Raajimakers").

The rejections are respectfully traversed.

Claim 40 is amended to recite:

"(a) providing a reactor having a single reaction space;

(b) concurrently loading the plurality of wafers having a processing surface into the reaction space, wherein the processing surfaces of the wafers face in substantially the same direction;

(c) introducing a first reactant into the reaction space, wherein a portion of the first reactant is chemically adsorbed on the processing surface of each of the plurality of wafers;

(d) *diluting a non-chemically adsorbed portion of the first reactant in the single reaction space,*

*wherein said introducing the first reactant is performed at a first pressure and said diluting the non-chemically adsorbed portion of the first reactant is performed to a second pressure, and wherein the second pressure is greater than the first pressure;*

(e) removing the non-chemically adsorbed portion of the first reactant from the reaction space;

(f) introducing a second reactant into the reaction space, wherein a portion of the second reactant is chemically adsorbed on the processing surface of each of the plurality of wafers;

(g) *diluting a non-chemically adsorbed portion of the second reactant in the single reaction space*; and

(h) removing the non-chemically adsorbed portion of the second reactant from the reaction space,” the limitations drawn from allowed claim 1. (Emphasis added)

None of the cited references teach or disclose the above limitations of claim 40. Therefore, claim 40 is allowable and claim 41, which depends therefrom and recites a feature that is neither taught nor disclosed in the cited references, is also allowable. For the same reasons, new claim 43 is also allowable.

For the foregoing reasons, reconsideration and allowance of claims 1, 4-22 and 24-43 of the application as amended is solicited. The Examiner is encouraged to telephone the undersigned at (503) 222-3613 if it appears that an interview would be helpful in advancing the case.

**Customer No. 20575**

Respectfully submitted,

MARGER JOHNSON & McCOLLOM, P.C.



Alan T. McCollom  
Reg. No. 28,881

MARGER JOHNSON & McCOLLOM, P.C.  
1030 SW Morrison Street  
Portland, OR 97205  
503-222-3613